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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Tipton, et al.

Attorney Docket No.: NOVLP075/NVLS-000820

Application No.: 10/672,311

Examiner: COLEMAN, WILLIAM D

Filed: September 26, 2003

Group: 2823

Title: METHOD OF POROGEN REMOVAL  
FROM POROUS LOW-K FILMS  
USING UV RADIATION

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on July 7, 2006 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

Leslie Russell

**PETITION TO ACCEPT AN UNINTENTIONALLY  
DELAYED CLAIM FOR THE BENEFIT OF A PRIOR-FILED APPLICATION  
37 CFR §1.78(a)(6)**

Mail Stop DAC  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants hereby petition for the acceptance of an unintentionally delayed reference to a claim for priority under 35 USC §119(e). The entire delay between the date the reference was due under 37 CFR §1.78(a)(5)(ii) and the date of filing this petition was unintentional.

**Fees:**

☒ Check No. 12155 in the amount of \$1370.00 is enclosed for the petition fee (37 C.F.R. 1.17(t)).

☒ The Commissioner is authorized to charge any fees beyond the amount enclosed which may be required, or to credit any overpayment, to Deposit Account No. 500388 (Order No. NOVLP075).

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☒ Amend the specification by replacing the paragraph beginning at page 1, line 5 as follows:

**CROSS-REFERENCE TO RELATED APPLICATIONS**

This application is a continuation-in-part claiming priority under 35 USC 120 from US Patent Application No. 10/404,693, filed on March 31, 2003, titled "Method for Forming Porous Films by Porogen Removal Combined with In Situ Surface Modification," by Raashina Humayun et al. as inventors, which application is incorporated herein by reference in its entirety for all purposes. This application also claims the benefit of U.S. Provisional Patent Application No. 60/469,433 filed May 9, 2003 naming Tipton et al. as inventors and titled "METHOD OF POROGEN REMOVAL FROM POROUS LOW-K FILMS USING UV IRRADIATION," which is incorporated herein by reference in its entirety for all purposes. This application is also related to US Patent Application No. 10/672,305 (~~Attorney Docket NOVL069~~) filed on the same day as the instant application, titled "Method for Removal of Porogens from Porous Low-k Films Using Supercritical Fluids," by Adrienne Tipton et al. as inventors and to US Patent Application No. 10/295,965 filed November 15, 2002 by Schulberg, et al., and titled "System for Deposition of Mesoporous Materials," which applications are incorporated herein by reference in its entirety for all purposes.

Respectfully submitted,  
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